This international standard was developed in accordance with internationally recognized principles on standardization established in the Decision on Principles for the Development of International Standards, Guides and Recommendations issued by the World Trade Organization Technical Barriers to Trade (TBT) Committee.

Designation: F459 – 13 (Reapproved 2018)

Standard Test Methods for Measuring Pull Strength of Microelectronic Wire Bonds[1]

This standard is issued under the fixed designation F459; the number immediately following the designation indicates the year of original adoption or, in the case of revision, the year of last revision. A number in parentheses indicates the year of last reapproval. A superscript epsilon (ε) indicates an editorial change since the last revision or reapproval.

This standard has been approved for use by agencies of the U.S. Department of Defense.

1. Scope

1.1 These test methods cover tests to determine the pull strength of a series of wire bonds. Instructions are provided to modify the methods for use as a referee method. The methods can be used for wire bonds made with wire having a diameter of from 0.0007 to 0.003 in. (18 to 76 µm).

NOTE 1—Common usage at the present time considers the term "wire bond" to include the entire interconnection: both welds and the intervening wire span.

1.2 These test methods can be used only when the loop height of the wire bond is large enough to allow a suitable hook for pulling (see Fig. 1) to be placed under the wire.

1.3 The precision of these methods has been evaluated for aluminum ultra-sonic wedge bonds; however, these methods can be used for gold and copper wedge or ball bonds.[2]

1.4 These methods are destructive. They are appropriate for use in process development or, with a proper sampling plan, for process control or quality assurance.

1.5 A nondestructive procedure is described in Practice F458.

1.6 The values in SI units are to be regarded as standard.

1.7 *This standard does not purport to address all of the safety concerns, if any, associated with its use. It is the responsibility of the user of this standard to establish appropriate safety, health, and environmental practices and determine the applicability of regulatory limitations prior to use.*

1.8 *This international standard was developed in accordance with internationally recognized principles on standardization established in the Decision on Principles for the Development of International Standards, Guides and Recommendations issued by the World Trade Organization Technical Barriers to Trade (TBT) Committee.*

2. Referenced Documents

2.1 *ASTM Standards:*[3]

F458 Practice for Nondestructive Pull Testing of Wire Bonds

3. Terminology

3.1 *Definitions of Terms Specific to This Standard:*

3.1.1 For the purposes of these test methods the following failure points are defined:

3.1.2 *bond-wire junction failure*—a rupture in the wire within two wire diameters of the bond and in which more than 25 % of the bonded area is left on the pad after the pull test has been applied.

3.1.3 *weld interface failure*—a rupture in which less than 25 % of the bonded area is left on the pad after the pull test has been applied. See pad lifting in 6.6.

3.1.4 *wire span failure*—a rupture in the wire other than *(1)* at a point within two wire diameters of either bond, or *(2)* at the point at which the hook contacted the wire.

4. Summary of Test Methods

4.1 The microelectronic device with the wire bond to be tested is held firmly in an appropriate fixture. A hook is positioned under the wire midway between the two bonds. The hook is then raised until the wire bond breaks. The force applied to the hook in order to cause failure of the wire bond is recorded. The point of failure is observed and recorded. In the referee method, the force in the wire on breaking is calculated.

5. Significance and Use

5.1 Failure of microelectronic devices is often due to failure of an interconnection bond. A common type of interconnection bond is a wire bond. These methods can assist in maintaining control of the process of making wire bonds. They can be used

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[1] These test methods are under the jurisdiction of ASTM Committee F01 on Electronics and are the direct responsibility of Subcommittee F01.03 on Metallic Materials, Wire Bonding, and Flip Chip.

Current edition approved March 1, 2018. Published April 2018. Originally approved in 1976 as F459 – 76 T. Last previous edition approved in 2013 as F459 – 13. DOI: 10.1520/F0459-13R18.

[2] Harman, G. G., "Microelectronic Ultrasonic Bonding," *NBS Special Publication* 400-2, pp. 94-95 and "Wire Bonding in Microelectronics," Third Edition, McGraw Hill, 2010. Also Microelectronics Reliability 51 (2011), Special Issue on Copper bonding.

[3] For referenced ASTM standards, visit the ASTM website, www.astm.org, or contact ASTM Customer Service at service@astm.org. For *Annual Book of ASTM Standards* volume information, refer to the standard's Document Summary page on the ASTM website.

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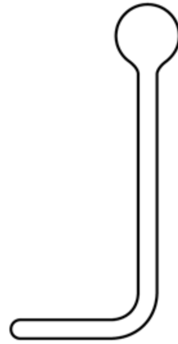

FIG. 1 Suggested Configuration for a Pulling Hook

to distinguish between weak, nonadherent wire bonds and acceptably strong wire bonds. The methods are destructive.

5.2 These test methods are appropriate for on-line use for process control, for purchase specifications, and for research in support of improved yield or reliability. The referee method should be used for quantitative comparison of pull strengths of wire bonds.

6. Interferences

6.1 Failure to center the hook along the loop between the two bonds or pulling in a direction not lying in the plane containing the undisturbed loop may invalidate the test since an unbalanced distribution of forces between the two bonds may result.

6.2 Slippage of the hook along the wire span during pulling may invalidate the test because an unbalanced distribution of forces between the two bonds may result.

6.3 Careless insertion of the hook may damage either bond or wire and thus invalidate the test.

6.4 The presence of vibration or mechanical shock may cause the application of an extraneous force and thus invalidate the test.

6.5 Measured bond-pull force is strongly dependent on the height of the loop ($H + h$, as defined in 11.1.1) and the bond-to-bond spacing (d, as defined in 11.1.1).

6.6 For fine pitch ball bonds (<60 µm pitch), the bond pad may tear and lift during pull testing. Current practice is to accept this if the pull force is acceptably high under agreed upon requirements, but note it as appropriate. In some cases of bad peeling, it is necessary to move the pulling hook directly over the top of the ball bond. This should be noted.

7. Apparatus

7.1 *Bond-Pulling Machine*—Apparatus for measuring wire-bond pull strength with the following components:

7.1.1 *Hook*—Pulling hook made from a rigid wire such as tungsten. The diameter of that part of the hook that contacts the wire loop should be approximately 2.5 times the diameter of the wire used to make the wire bond. A suggested hook configuration is shown in Fig. 1. The hook should appear under visual inspection to have a smooth polished surface with no sharp edges in any part of the hook that contacts the wire loop. The hook should be rigidly mounted in the pulling apparatus.

7.1.2 *Lifting-and-Gaging Mechanism* —Mechanism for applying a measured vertical force to the hook. The mechanism shall incorporate a means for recording the maximum force applied and shall be capable of applying force at a rate constant to within 2 gf/s (20 mN/s) in the range from 1 to 30 gf/s (10 to 290 mN/s) inclusive. A mechanism with a single fixed scale shall have a maximum scale reading no greater than three times the nominal bond pull strength anticipated.

NOTE 2—Mechanisms of the dynamometer type known as "gram gages" have been found satisfactory, but currently, electronic gauges (properly calibrated using the manufacturers' procedures) are more common.

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7.1.3 *Microscope with Light Source* —Zoom microscope with light source with a magnification range of approximately 14× to 60× with the eyepiece not to exceed 10×, for viewing the device under test.

7.1.4 *Device Holder*— Mechanism for holding the device under test *(1)* in a horizontal position, for Method A, or *(2)* in either a horizontal or a tipped position so that both bonds are in the same horizontal plane, for Method B. For the referee Method C, the device holder should provide a measurement, to within 2°, of the angle from the horizontal (which may be zero) through which the device has been tipped.

7.1.5 *Calibration Masses*—At least five masses (weights) with mass values known to within 0.5 % sized to cover the lifting-and-gaging mechanism range of force measurement, and suitably configured so that they may be supported by the pulling mechanism for calibration.

8. Sampling

8.1 Since the pull-test method is destructive, it shall be performed on a sampling basis. The sample selected should be representative of the wire bonds of interest. The size of the sample and the method of selection shall be agreed upon by the parties to the test.

9. Calibration

9.1 Calibrate the bond-pulling machine at the beginning of each series of tests, or daily if a series spans more than one day.

9.2 Assemble the bond-pulling machine in the same configuration to be used to perform the wire-bond pull test.